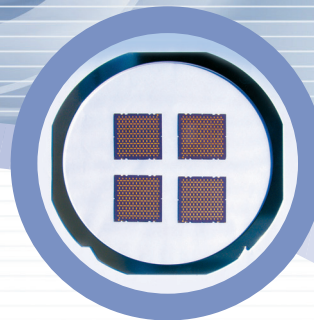
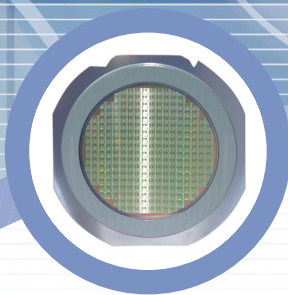
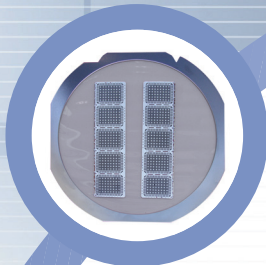


WCS-977



ADT 977 Wafer Cleaning System

ADT 977 Wafer Cleaner System is designed for cleaning workpieces after dicing.

Effective Cleaning Methods

The unit is equipped with a spinning chuck table and a rotating cleaning arm. It can be configured with Atomizing Cleaning Nozzle or High Pressure Nozzle, providing comprehensive cleaning solution to a wide range of workpiece types.

Easy Operation

ADT 977 is user friendly. An intuitive display control allows the user to set the desired cleaning sequences, spinning velocity and duration. Up to 8 recipes can be stored to match each workpiece specific requirements.

The unit supports real-time performance, monitoring and displaying status, total process time and alarms during operation.

Wide Range Of Workpieces

Two basic models are available:

ADT 977 supports up to 8" diameter workpieces. **ADT 977L** supports up to 12" diameter workpieces. A variety of chuck tables and frames can be configured.

System Highlights

- Compact design
- Atomizing or High pressure cleaning
- Easy to use - one touch activation with automatic lead cover closing
- Intuitive operating panel
- Process monitoring through status and alarms displays
- Light tower and buzzer
- Compliance with stringent safety standards
- Environment friendly



Ideal Choice for Single Frame Processing

ADT = **Dicing**
Advanced Dicing Technologies

WCS-977



Standard Features:

- Atomizing cleaning
- Air and nitrogen separation
- Nitrogen and water adjustable pressure gages
- Internal vacuum generator to hold the workpiece
- Air puff release
- Safety interlock
- Automatic covering /opening

Options:

- Chucks
 - Ceramic 5", 6", 8", 12"
 - Grip rings
 - Unmounted wafers
- Mist suction
- Ionizer- elimination of static charge
- Cleaning additives
- Drain separation
- High pressure pump
- CO₂ injection
- Water resistivity monitoring



977's User Interface

Ideal Choice for Single Frame Processing

Specifications:

Max workpiece size	Ø 200 mm (8")	Ø 300 mm (12")
Cleaning method	Atomizing Cleaning / High pressure cleaning	Atomizing Cleaning / High pressure cleaning
Number of recipes that can be saved	8	8
Spinner velocity range	200-3,000 rpm	200-2,000 rpm
Utilities requirements:		
Power supply	110/220 VAC 50/60Hz, single phase	110/220 VAC 50/60Hz, single phase
Power consumption During cleaning-	300 Watt; During Standby- 50 Watt	300 Watt; During Standby- 50 Watt
Air/Nitrogen pressure	4-5 bar	4-5 bar
Max water flow	1,000 mL/min	1,000 mL/min
Water pressure	3-5 bar	3-5 bar
Exhaust	100 CFM	100 CFM
Machine dimensions (WxDxH)	410X625X946 mm	520X809X946 mm
Machine net Weight .	120 Kg	200 Kg



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